Appl. No. «10/813,407» Amdt dated December 20, 2005

## **Amendments to the Specification:**

Please replace a paragraph at the bottom of page 33 with the following amended paragraph:

[0083] Note that scanning across several regions may be implemented in any manner well known in the art. Some embodiments scan the beam(s) along one axis using a galvanometer and move the stage along the other axis. For example, as shown in FIG. 4B, stage [[439]] 459 may be scanned along the X axis while the optics may be scanned along the Y axis. The details of the scanning mechanisms used are not critical aspects of the invention. Note that scanning along both axes could be implemented with stage motion or alternatively by a 2-axis galvanometer.

SILICON VALLEY
PATENT GROUP ILP

2350 Mission College Blvd Suite 360 Santa Clara, CA 95054 (408) 982-8200 FAX (408) 982-8210